

SYSTEM AND METHOD FOR MEASURING PROPERTIES OF A
SEMICONDUCTOR SUBSTRATE IN A NON-DESTRUCTIVE WAY

Clarysse et al.

Appl. No.: Unknown

Atty Docket: IMEC281.001AUS

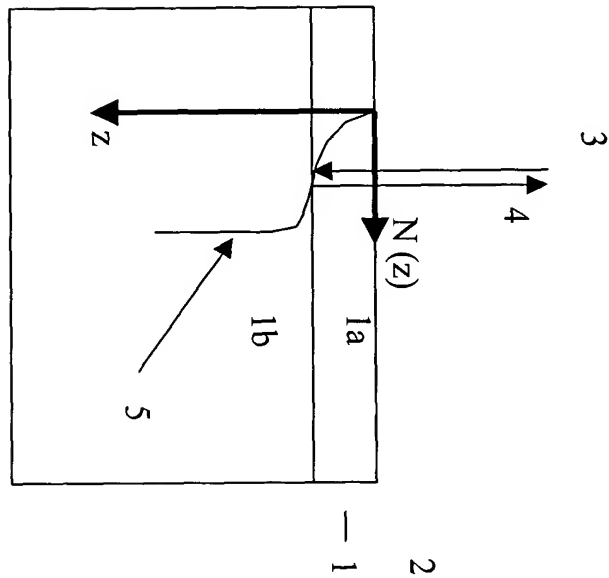


Figure 1

Figure 2

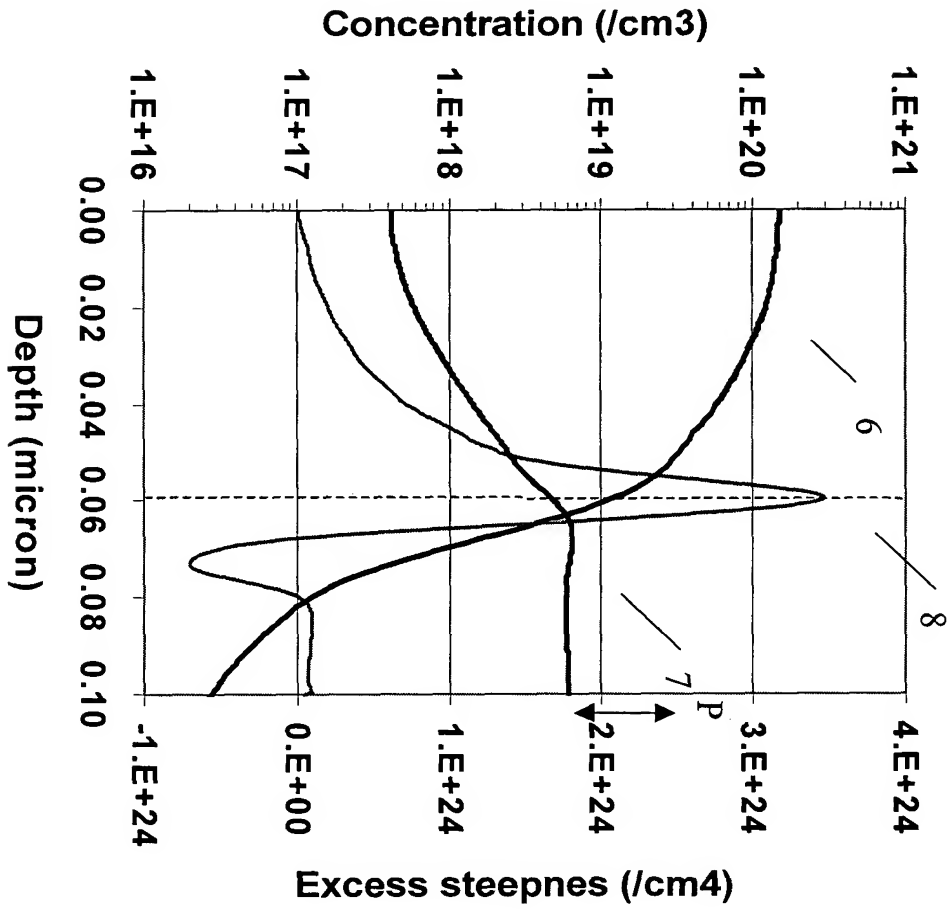


Figure 3a

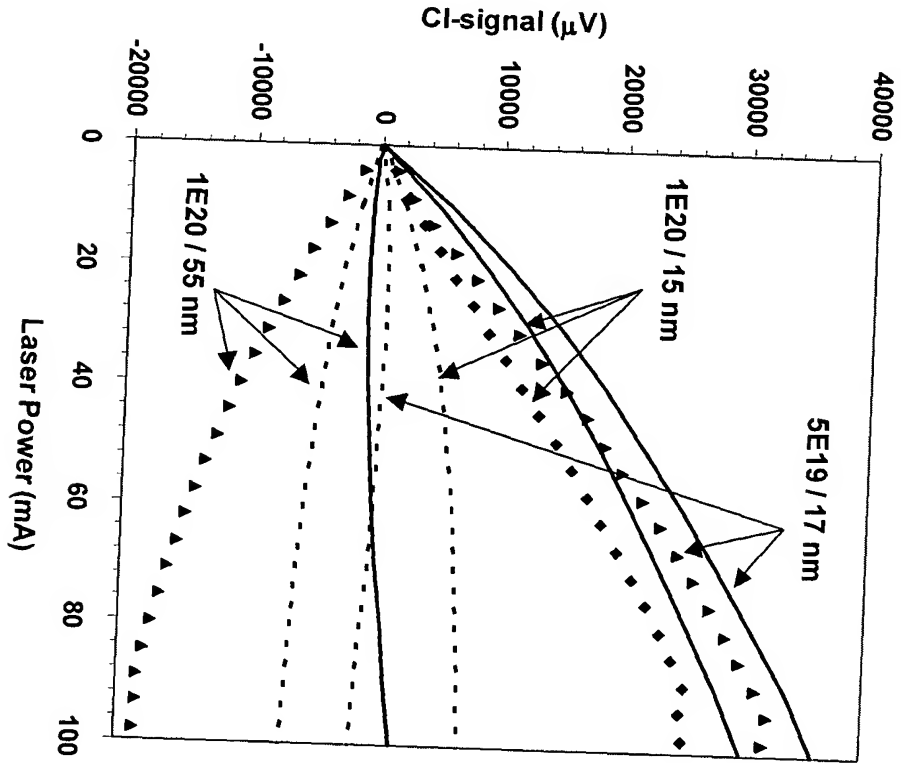
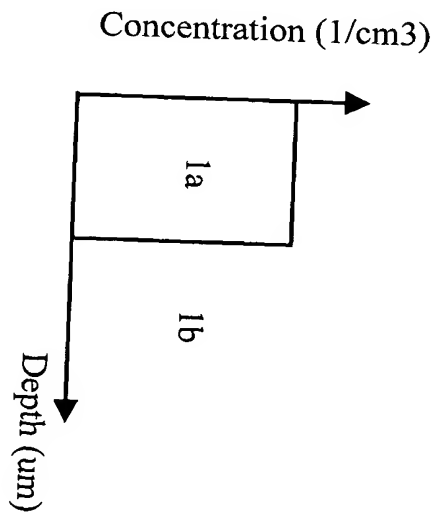


Figure 3b



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Figure 4

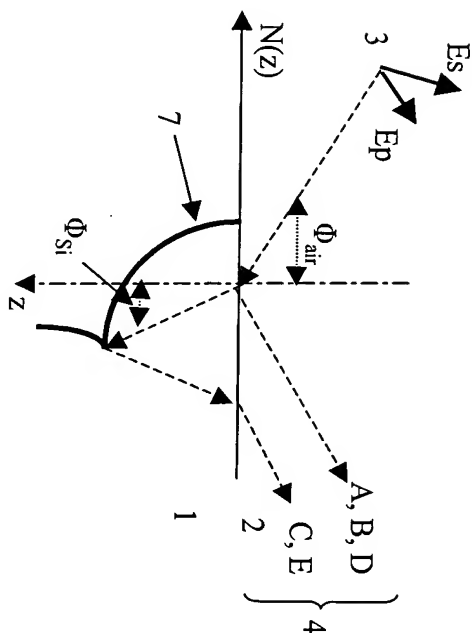


Figure 5

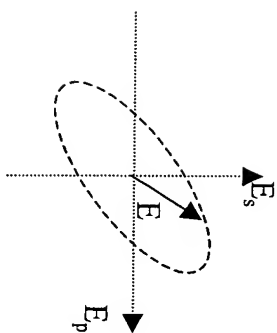


Figure 6a

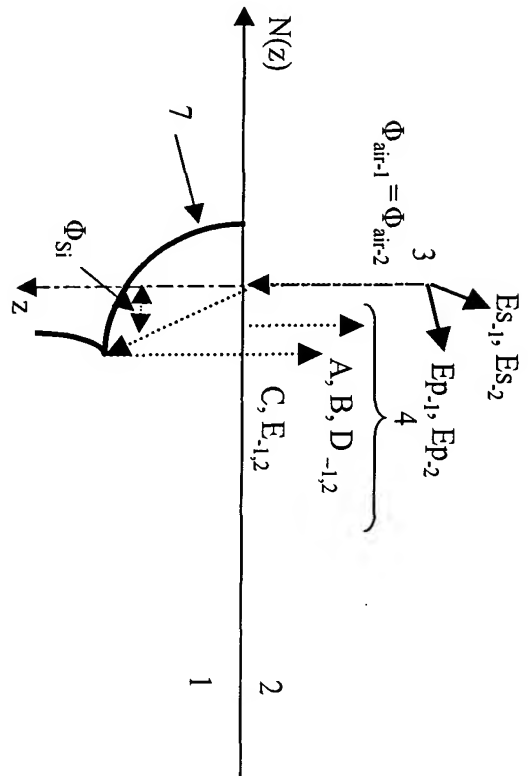


Figure 6b

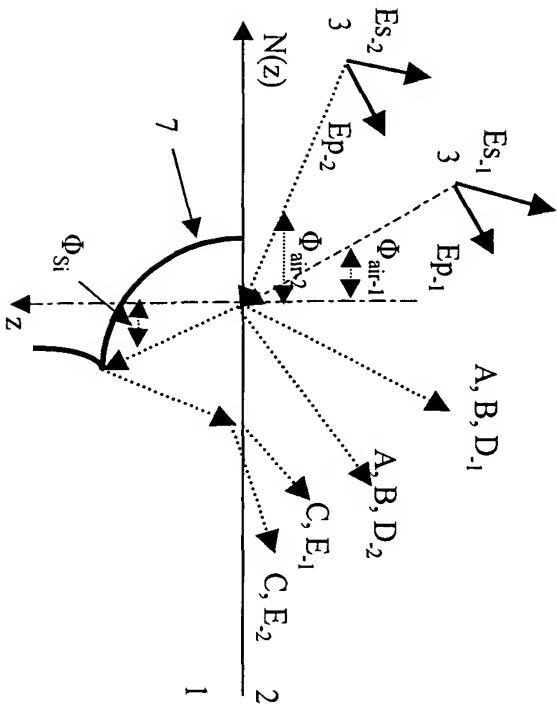
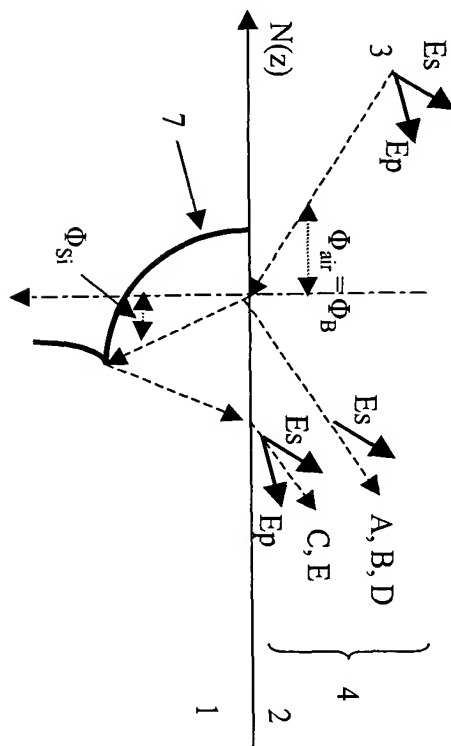


Figure 7



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Figure 9

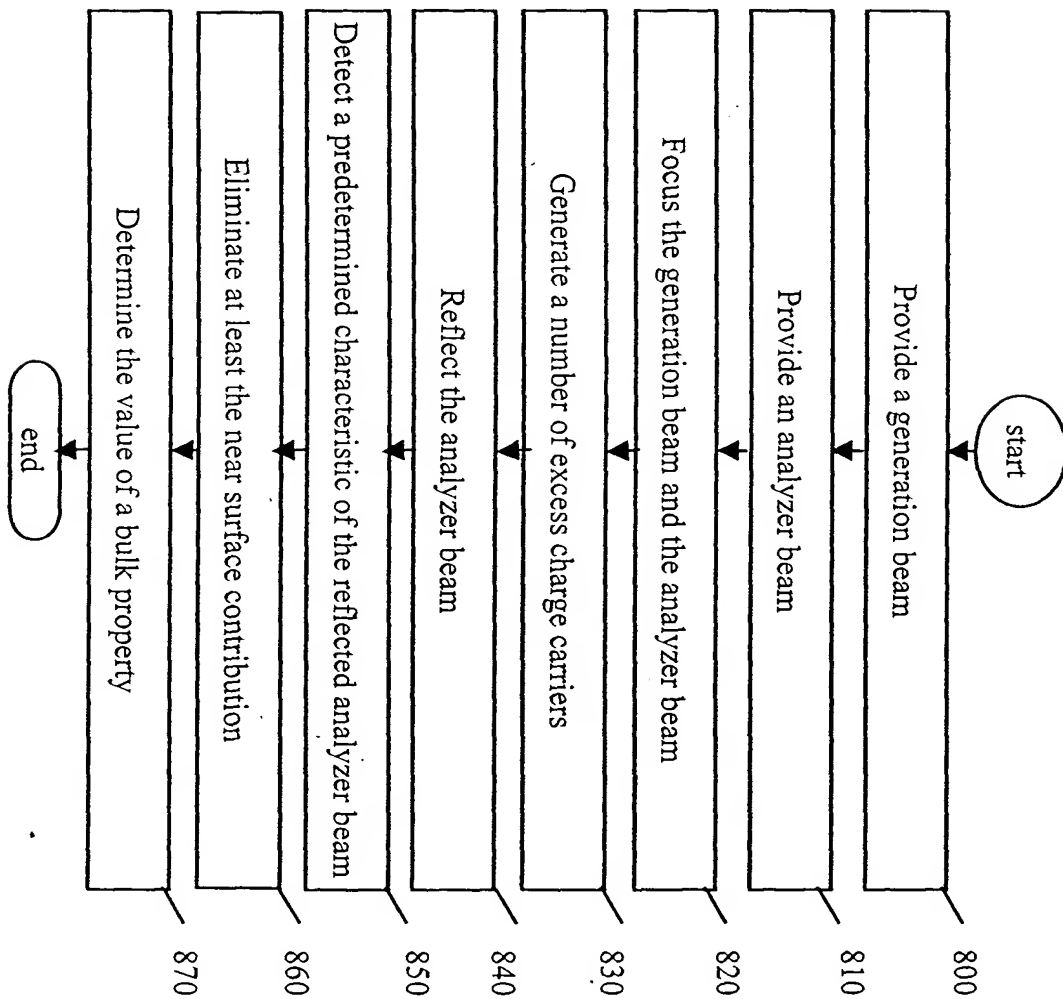


Figure 10

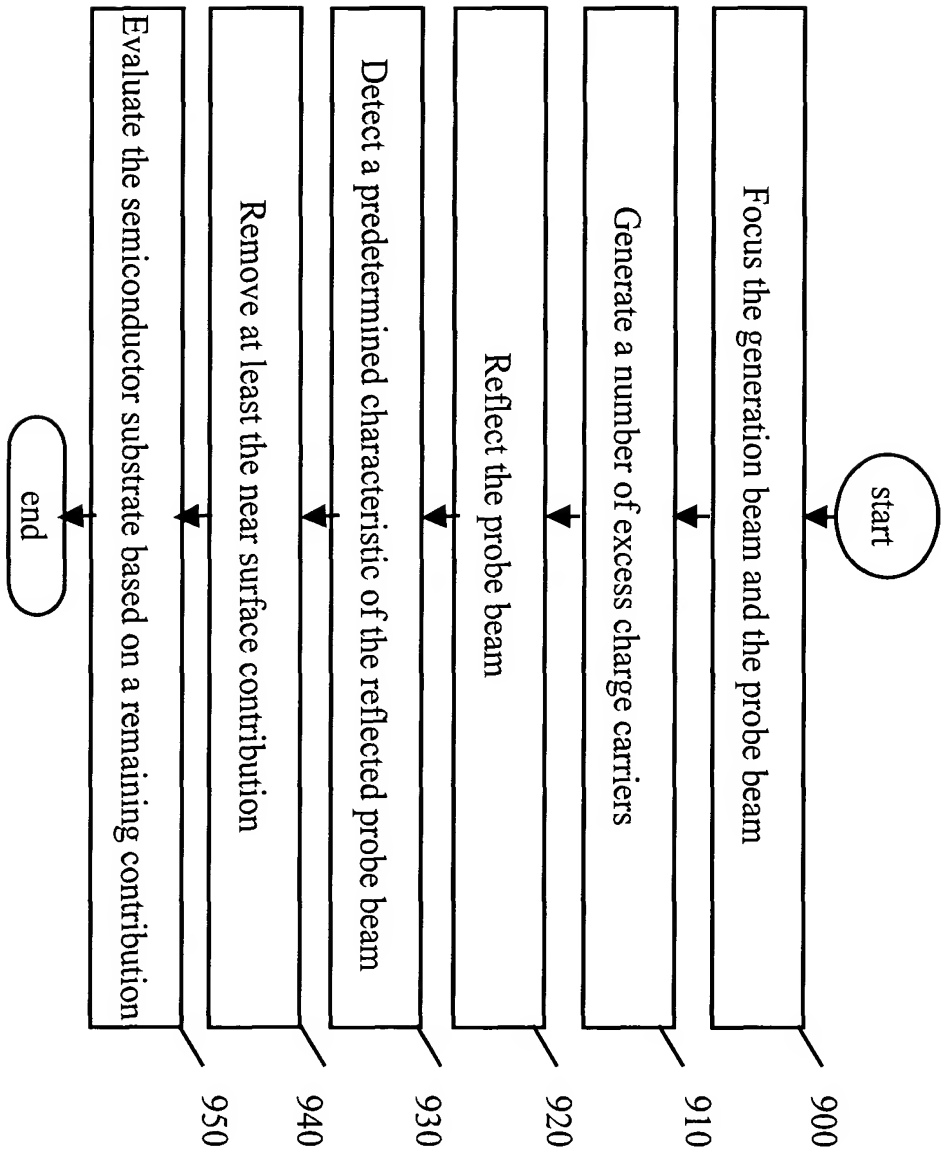


Figure 11

